

ABSTRACT

A monitoring system for monitoring surroundings of a substrate processing apparatus installed in a cleanroom includes a detection tape disposed on upper surfaces of some or all of the floor tiles surrounding the substrate processing apparatus, the detection tape extending across a plurality of floor tiles, wherein the detection tape includes a conductive layer disposed along a longitudinal direction of the tape, and the monitoring system further includes an alarm unit configured to generate an alarm when electrical continuity in the conductive layer is interrupted or when a voltage of a signal current flowing through the conductive layer falls below a predetermined threshold value.

FIG. 2